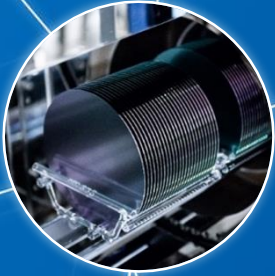


**Artificial  
Intelligence**



**5G**

# Enabling best-in-class GaN-on-Si devices for 5G: epitaxy

Dr. Marianne Germain, Soitec  
SERENA EU project – Webinar November 4<sup>th</sup>, 2021



**Energy  
Efficiency**



# Outline

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- 1 GaN-on-Si: an innovation enabler for RF
- 2 The differentiating features of Soitec's GaN technology at the bottom of the SERENA project
- 3 Summary



1

# GaN – an innovation enabler in the RF market



# Soitec products portfolio mobile communications

## APPLICATIONS

- Smartphones radio-frequency front-end modules
- Networking base stations



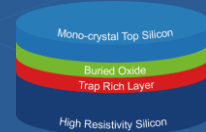
## SOITEC PRODUCTS ENABLE

- 4G
- 5G
- WiFi 6 connectivity



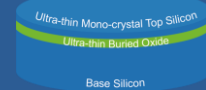
### RF-SOI

For highly efficient mobile communication



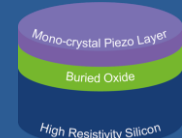
### FD-SOI

Integrated technology



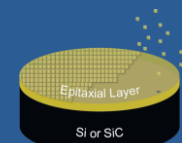
### POI

High performance 5G filters

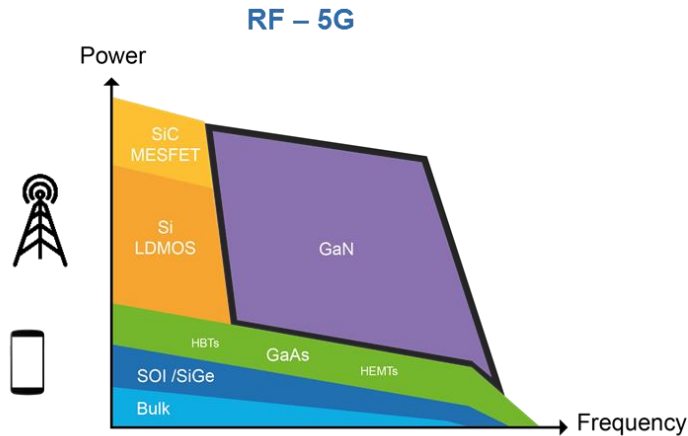


### GaN

High performance power amplifier



# GaN epitaxial wafers - enabling technology for 5G



Source: Figure adapted from Analog Device 2017

- **Cellular base stations (>5W power amplifier)**
  - GaN - becoming mainstream for 4G / 5G <6GHz and mmW
- **Cellular handset (<3W Power amplifier)**
  - GaAs – mainstream technology for 4G / 5G <6GHz
  - GaN – advantage for 5G mmW

## Market outlook



**EpiGaN SAM in CY26**  
**~300 k wafers (150mm eq.)**

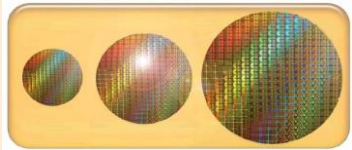
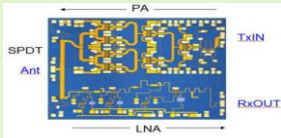
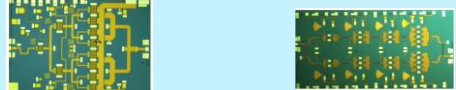
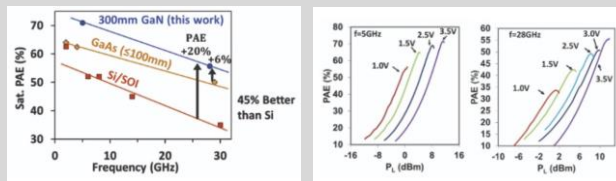
Future opportunities on power automotive & sensors





# RF GaN/Si - an attractive technology for 5G mmwave



| Technology Criteria  | RF GaN/Si proof points   | Demos, chip designs, data   |
|--|--|---|
| Economies of Scale   | <ul style="list-style-type: none"> <li>✓ 150mm, 200mm GaN/Si epiwafers available in volume today</li> <li>✓ 300mm GaN/Si technology in development</li> <li>✓ Compatible with Si CMOS fab</li> </ul>   |    |
| Integration  | <ul style="list-style-type: none"> <li>✓ 30GHz GaN/Si transceiver MMIC with integrated 4W PA, LNA and switch</li> </ul>  |  <p>Source: OMMIC</p> <p>Figure 7b: Ka band Transmit/Receive chip photograph</p>       |
| Bandwidth, Frequency   | <ul style="list-style-type: none"> <li>✓ Wide bandwidth performance, single PA covering multiple bands</li> <li>✓ From 5G (sub6, mmW) to 6G bands</li> </ul>   | <p>14-18GHz 20W GaN/Si PA      94-100GHz 0.5W GaN/Si PA</p>  <p>Source: MC2, OMMIC</p> |
| High or Low Voltage Operation possible - associated to highest PAE | <ul style="list-style-type: none"> <li>✓ High Breakdown Voltage (<math>V_{DS} &gt; 28-50V</math>)</li> <li>✓ Low supply (knee) voltage due to                             <ul style="list-style-type: none"> <li>• Ultra-low <math>R_s</math> GaN HEMTs (e.g. InAlN &lt; 250 Ohm/sq) &amp;</li> <li>• Low ohmic contact resistance (<b>ohmic regrowth by MOCVD</b>)</li> </ul> </li> <li>✓ Significantly improved <b>PAE</b> for all 5G bands with GaN (e.g. longer battery life times)</li> </ul> |  <p>Source: Intel</p>  |



2

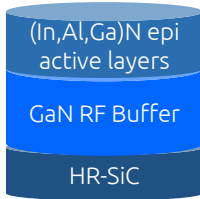
## The differentiating features of Soitec's GaN technology at the bottom of the SERENA project



# Soitec's GaN epitaxial current product offering

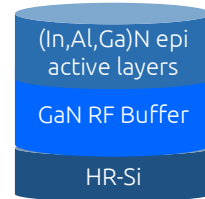
RF

## GaN - on - SiC



- 100 & 150 mm
- Sub-6GHz or mmwave

## GaN - on - Si



- 150 & 200 mm
- Sub-6GHz or mmwave

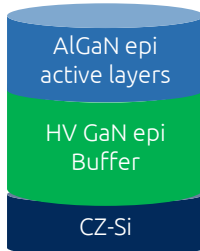


**Power Amplifiers  
& Front-ends**

**Infrastructure  
& Handsets**

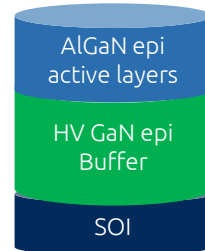
Power

## GaN - on - Si



- 200 mm
- Discrete HEMTs or ICs
- Normally-on or normally-off
- 200V or 650V

## GaN - on - SOI



- 200 mm
- ICs and SoCs
- Normally-on or normally-off
- 200V or 650V

## Efficient Power



**Power supply, fast  
chargers**

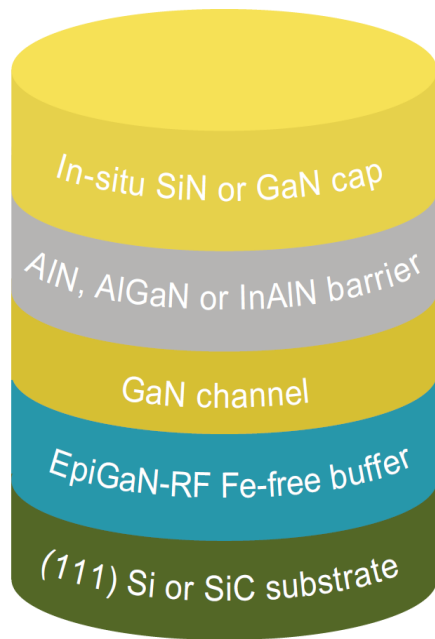


**EV  
Automotive**

*under development*



# Soitec's RF GaN products provide differentiation for 5G



## **In-situ SiN, optional GaN cap**

In-situ SiN as a high-quality gate dielectric, robust surface passivation

## **Optimized heterostructures available**

- AlGaIn/SiN or AlGaIn/GaN for sub6GHz
- AlN/SiN, InAlN for mmW bands

## **State-of-the-art Fe-free RF buffers**

excellent DC resistivity&breakdown, RF losses and dynamic performance

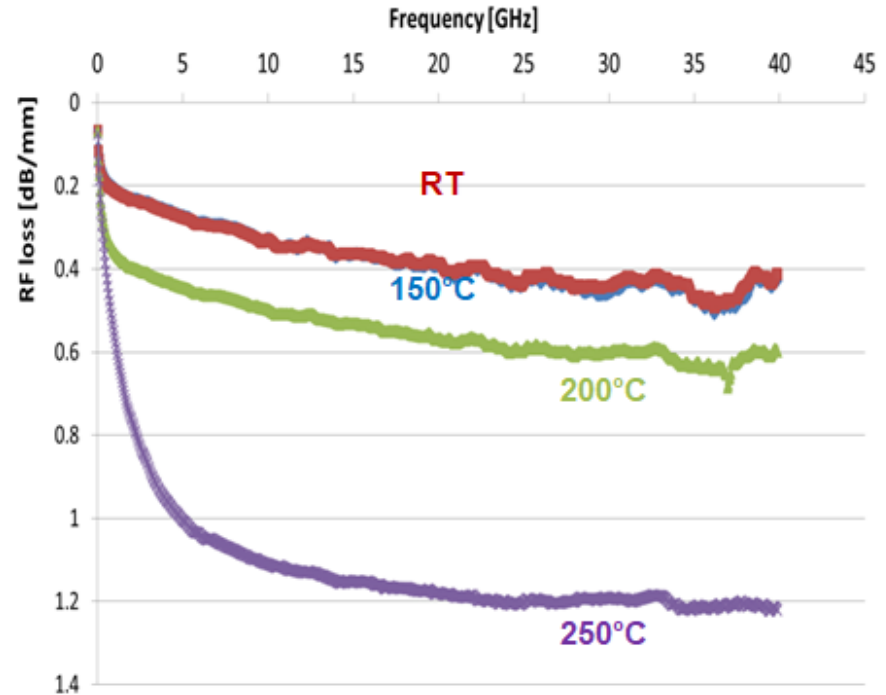
## **On Silicon or SiC substrates**

up to 200mm Si, up to 150mm SiC

# High Temperature assessment of RF losses in GaN/Si



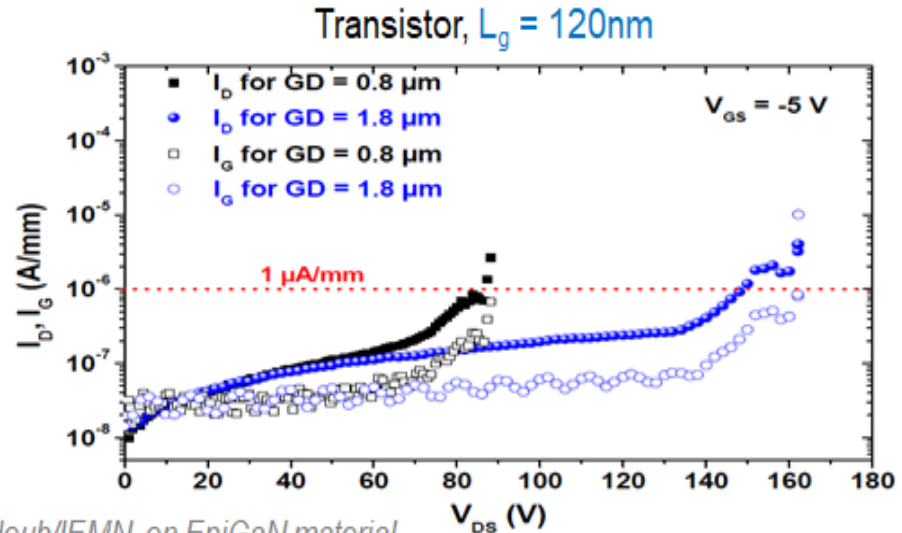
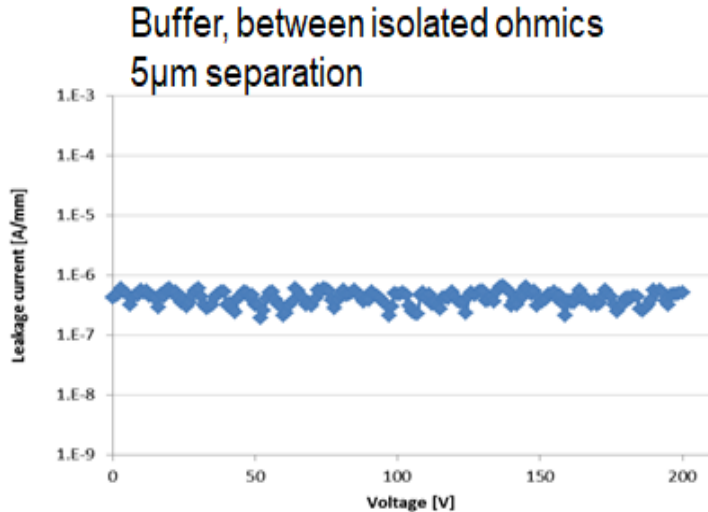
- > Losses for GaN-on-Si are very comparable to GaN-on-SiC up to 20 GHz
- > Losses remain low (< 0.8 dB/mm) up to 100 GHz!
- > on 200 mm HR CZ- Si(111)



RF losses remain below 1db/mm up to **200°C**

# DC Breakdown Voltage Material

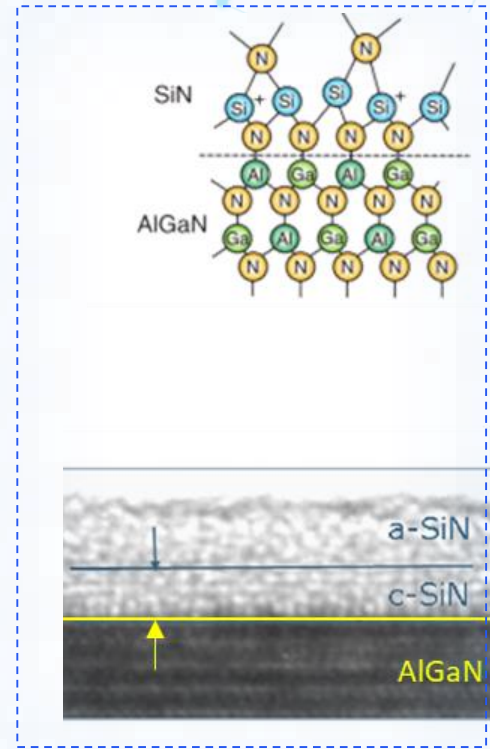
- Lateral Breakdown Voltage:  $E_c \sim 1\text{MV/cm}$
- Leakage current  $< 1\mu\text{A/mm}$  until device breakdown



Courtesy of: F. Medjdoub/IEMN, on EpiGaN material

# In-situ SiN – more than surface passivation

- › ‘Very early’ and efficient passivation approach
- › High-density SiN
- › High-quality gate dielectric
- › Higher  $n_s$  and mobility compared to GaN cap
- › Prevents relaxation of (Al,Ga)N barrier
- › Improved thermal stability, device reliability
- › Reduces contamination risks in CMOS fabs



# Tuning the heterostructure for the required RF/mm-wave performance

- Reference structure today mostly use **AlGaN/GaN heterostructures** with either SiN or GaN cap  
*(reference structure today used in 3G/4G <sub6Ghz & X Band )*  
Typical electrical specifications:
  - $\mu > 1800 \text{ cm}^2/\text{V.s}$  for  $n_s \sim 1 \text{ e}^{13}/\text{cm}^2$  with SiN cap
  - Offers Low leakage for Schottky and (SiN) MIS-HEMTs
- **BUT mm-wave requires more advanced type of heterostructures**



# mmwave operation : possible strategies

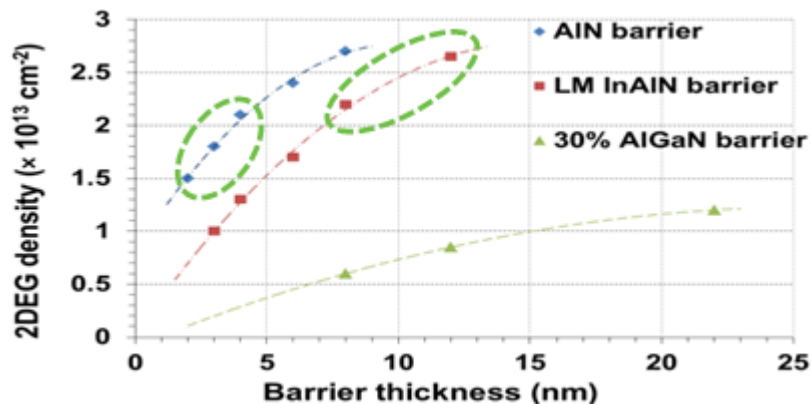
- Heterostructures for maximal  $g_m$

- ◆ Gate-to-channel aspect ratio

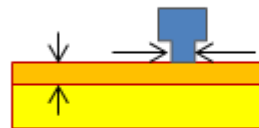
- Ultrathin AlN

- ◆ Maximise  $I_{ds} \Rightarrow$  Reduction of  $R_{sheet}$

- InAlN with  $R_{sheet} < 250$  Ohm/sq.



$$f_t \approx \frac{g_m}{2 \cdot \pi \cdot (C_{gs} + C_{gd})}$$



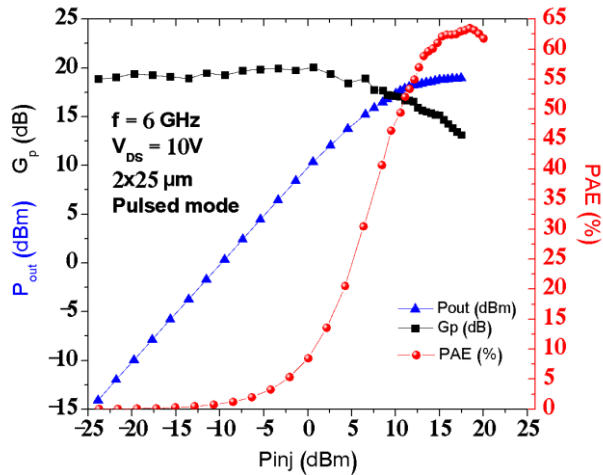
$$g_m = \frac{dI_{ds}}{dV_g}$$

Strain imposes different thickness regimes

# HVRF SiN/AlN HEMT on Si @6GHz

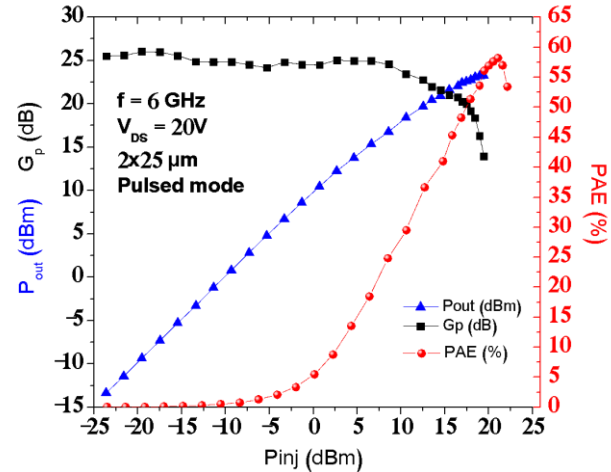
$V_{DS} = 10\text{ V}$

Saturated  $P_{OUT} = 1.6\text{ W/mm}$



$V_{DS} = 20\text{ V}$

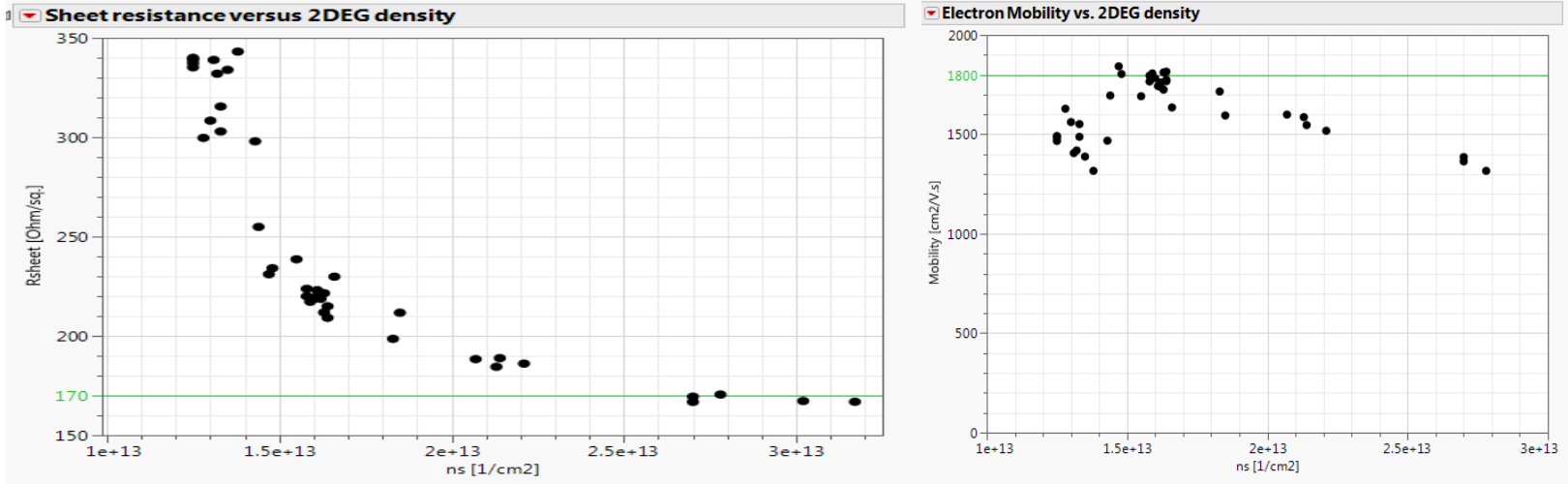
Saturated  $P_{OUT} = 4.2\text{ W/mm}$



Courtesy of: F. Medjdoub/IEMN;

**T-Gate: 150nm, no wafer thinning nor TSV, Deep class AB,  $I_D = 100\text{ mA/mm}$**

# InAlN carrier density mobility optimization

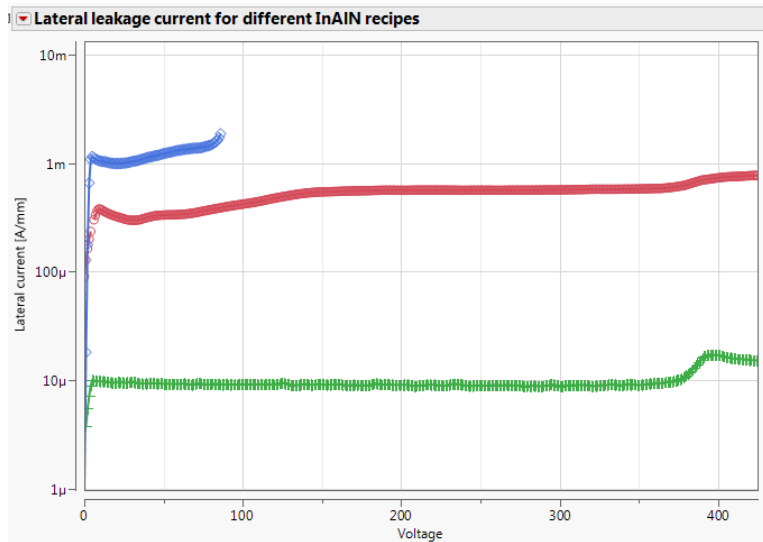


- **Excellent 2DEG transport properties:**

- ✓ Hall:  $n_s$  between  $1.3 \times 10^{13}/\text{cm}^2$  and  $3.2 \times 10^{13}/\text{cm}^2$  (depending on barrier thickness and composition)
- ✓  $R_s = 170 \text{ Ohm/sq}$  ( $\mu = 1,800 \text{ cm}^2/\text{V.s}$  @  $n_s = 1.6 \times 10^{13}/\text{cm}^2$ )

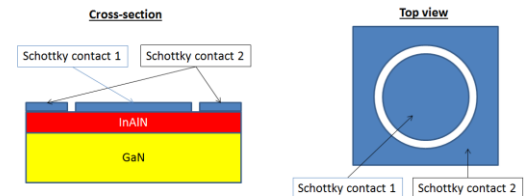
# Leakage current reduction with InAlN barriers

- MOCVD process tuning allows for
  - Leakage current reduction (down to  $10\mu\text{A}/\text{mm}$ )
  - Lateral breakdown voltage increase (buffer limit)



Measured between two concentric Ni/Au Schottky contacts in direct contact with InAlN barrier, with spacing  $14\mu\text{m}$

Normalised to periphery [A/mm]



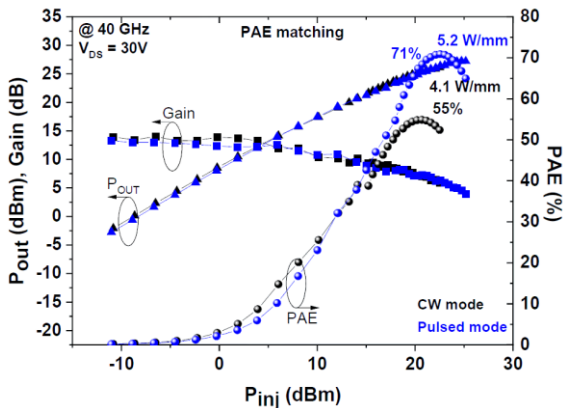
**Processing:**  
Metal is deposited on top of InAlN barrier in one lithographic step  
There is no dielectric nor mesa isolation

Diameter center contact =  $150\mu\text{m}$   
 $\Rightarrow$  Periphery =  $471\mu\text{m}$   
Spacing = 4, 12 or  $32\mu\text{m}$

# mmWave performance of Soitec epitaxial wafers

Active load-pull on 2x50um transistors with  $L_g = 110\text{nm}$

## AlN barriers

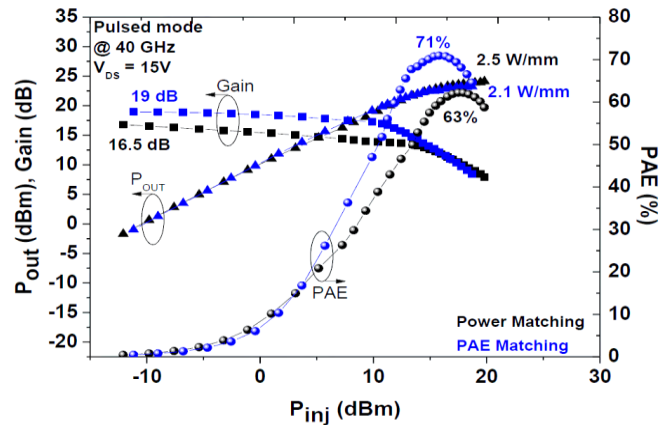


Robust HEMT  
Operating at 30V

SotA power density and PAE

Gain,  $F_t$ ,  $f_{max}$  limited by electron mobility

## InAlN barriers



SotA PAE and good power density

High gain due to much larger  $f_t$  /  $f_{max}$

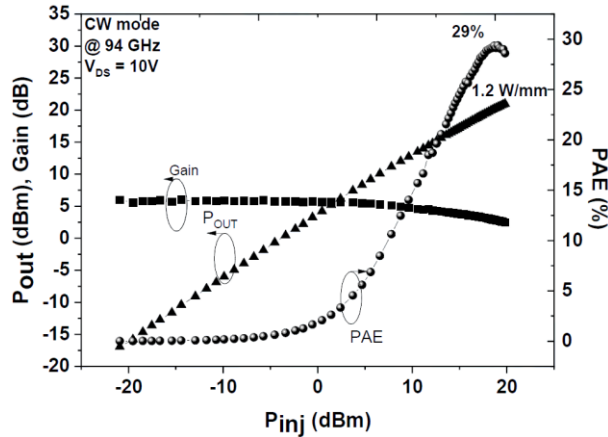
Robustness is a critical point of attention



# W-band performance of Soitec epitaxial wafers

Active load-pull on 2x25um transistors with  $L_g = 80\text{nm}$

## AlN barrier



SotA power density and PAE for 94GHz

Gain is rather low (due to  $f_t/f_{max}$ )

The performance of InAlN barriers with very short gate lengths ( $\ll 100\text{nm}$ ) needs to be explored to achieve high gain, PAE and power density at the same time.

## Take-Aways



- GaN-on-Si technology up to 200mm (next 300mm) epiwafers products enables most cost-efficient GaN technology deployment for volume by leveraging from Si fab manufacturing
- In-situ SiN capping offers not only optimal surface passivation but also enables ultimate performance barriers and is compatible with ohmic contact regrowth.
- Latest EpiGaN-RF product family developments with SiN/(In,Al)N top structures are a key enabler for sub-6GHz and mmW NR 5G applications



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